

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF THE CLAIMS:

1-10. (Canceled).

11. (Currently Amended) A yaw rate sensor, comprising:

a substrate;

a drive element;

a Coriolis element situated above a surface of the substrate;

a driving arrangement to drive the drive element parallel to a first axis at a frequency of oscillation; and

a force-conveying arrangement for conveying a dynamic action of a force between the substrate and the Coriolis element, wherein:

the Coriolis element is capable of being induced ~~by the drive element~~ to oscillate parallel to ~~[[a]]~~ the first axis,

a deflection of the Coriolis element in a second axis that is substantially perpendicular to the first axis is detectable,

the first axis and the second axis are parallel to the surface of the substrate, and

the force action has at least one frequency such that is an integral multiple of a frequency of oscillation of the drive element parallel to the first axis.

12. (Previously Presented) The yaw rate sensor as recited in claim 11, wherein the force-conveying arrangement directly conveys the dynamic action between the substrate and the Coriolis element.

13. (Previously Presented) The yaw rate sensor as recited in claim 11, further comprising:

a plurality of springs; and

a detection element coupled to the Coriolis element via the springs, wherein:

the force-conveying arrangement indirectly conveys the dynamic action between the substrate and the Coriolis element in such a manner that a direct force action is conveyed between the substrate and the detection element,
and the detection element is coupled to the Coriolis element by the springs in such a way that the dynamic action is conveyed between the substrate and the Coriolis element.

14. (Previously Presented) The yaw rate sensor as recited in claim 11, further comprising:
a detection arrangement via which a position of the drive element parallel to the first axis is detected.

15. (Currently Amended) The yaw rate sensor as recited in claim 11, ~~wherein the~~ further comprising:
a phase relationship arrangement to provide ~~dynamic action has~~ a fixed phase relationship ~~to~~ between the dynamic action and the oscillation of the drive element parallel to the first axis.

16. (Currently Amended) The yaw rate sensor as recited in claim 11, ~~wherein a~~ further comprising:
an adjusting arrangement to adjust a phase of the dynamic action conveyed by the force-conveying arrangement ~~is adjustable~~ in relation to the oscillation of the drive element parallel to the first axis.

17. (Currently Amended) The yaw rate sensor as recited in claim 14, ~~wherein the~~ further comprising:
a determining arrangement to determine ~~force-conveying arrangement is provided~~ ~~in such a way that~~ an amplitude of the dynamic action ~~is determined~~ by a deflection of the detection arrangement in the second axis.

18. (Currently Amended) A yaw rate sensor, comprising:
a substrate;
a drive element;

two Coriolis elements situated above a surface of the substrate and positioned symmetrically with respect to one another;

a mechanical coupling provided between the two Coriolis elements;

a driving arrangement to drive the drive element parallel to a first axis at a frequency of oscillation; and

a force-conveying arrangement for conveying a dynamic action of a force between the substrate and the Coriolis element, wherein:

the Coriolis elements are capable of being induced ~~by the drive element~~ to oscillate parallel to ~~[[a]]~~ the first axis,

a deflection of the Coriolis elements in a second axis that is substantially perpendicular to the first axis is detectable,

the first axis and the second axis are parallel to the surface of the substrate, and

the force action has at least one frequency such that is an integral multiple of a frequency of oscillation of the drive element parallel to the first axis.

19. (Currently Amended) The yaw rate sensor as recited in claim 11, ~~wherein~~ further comprising:

a shifting arrangement to shift a phase of a signal, wherein a frequency of the conveyed dynamic action is a product of an electromechanical multiplication, the multiplicand including a signal having the frequency of the oscillation of the drive element, and a multiplier including a signal having the frequency of the oscillation of the drive element with a phase shift to a multiplicand.

20. (Previously Presented) The yaw rate sensor as recited in claim 11, wherein a frequency of the conveyed dynamic action equals two times the frequency of the oscillation of the drive element.

21. (New) The yaw rate sensor as recited in claim 11, further comprising:

a plurality of springs; and

a detection element coupled to the Coriolis element via the springs, wherein:

the force-conveying arrangement indirectly conveys the dynamic action between the substrate and the Coriolis element in such a manner that a direct force action is conveyed between the substrate and the detection element,
and the detection element is coupled to the Coriolis element by the springs in such a way that the dynamic action is conveyed between the substrate and the Coriolis element;
wherein the force-conveying arrangement directly conveys the dynamic action between the substrate and the Coriolis element.

22. (New) The yaw rate sensor as recited in claim 11, further comprising:

a detection arrangement via which a position of the drive element parallel to the first axis is detected;

a phase relationship arrangement to provide a fixed phase relationship between the dynamic action and the oscillation of the drive element parallel to the first axis;

an adjusting arrangement to adjust a phase of the dynamic action conveyed by the force-conveying arrangement in relation to the oscillation of the drive element parallel to the first axis;

a determining arrangement to determine an amplitude of the dynamic action by a deflection of the detection arrangement in the second axis; and

a shifting arrangement to shift a phase of a signal, wherein a frequency of the conveyed dynamic action is a product of an electromechanical multiplication, the multiplicand including a signal having the frequency of the oscillation of the drive element, and a multiplier including a signal having the frequency of the oscillation of the drive element with a phase shift to a multiplicand.

23. (New) The yaw rate sensor as recited in claim 22, wherein a frequency of the conveyed dynamic action equals two times the frequency of the oscillation of the drive element.

24. (New) The yaw rate sensor as recited in claim 21, wherein a frequency of the conveyed dynamic action equals two times the frequency of the oscillation of the drive element.